Bifurcation of Polyelectrolyte Brushes Subject to Normal Electric Fields

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CAP May 31, 2013



Stimuli-Responsive MEMS Components "Smart" Surfaces



Responsive Materials Brushes

Stimuli-

Perpendicular Fields

Simulations Low Grafting Grafting High Grafting

Conclusion

Potential Bifurcating Brushes

Biology abounds with mesoscopic systems that dynamically and reversably respond to environmental cues

Stimuli-Responsive MEMS Components "Smart" Surfaces



Stimuli-Responsive Materials

Perpendicular

Low Grafting Grafting High Grafting

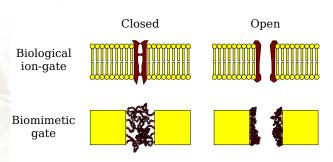
Conclusion

Bifurcating Brushes

Potential

Biology abounds with mesoscopic systems that dynamically and reversably respond to environmental cues

- If structures change radically with environment they can be engineered into
 - detectors
 - gates





Stimuli-Responsive MEMS Components "Smart" Surfaces



Stimuli-Responsive Materials

Perpendicular

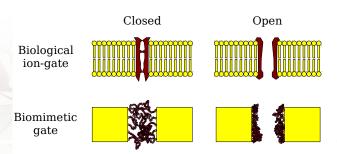
Low Grafting Grafting

High Grafting

Conclusion

Bifurcating Brushes

- Biology abounds with mesoscopic systems that dynamically and reversably respond to environmental cues
- If structures change radically with environment they can be engineered into
 - detectors
 - gates ← smart surfaces





Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields Simulations Low Grafting Density Intermediate Grafting Density High Grafting

Conclusion Potential

Applications Bifurcating Brushes Recapitulation • Different than neutral brush due to chain-counterion complex nature

 f is charge fraction of chain, z valency, N number of segments, H brush height, T counterion cloud thickness and Σ normalized grafting density

Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields Simulations Low Grafting Density Intermediate Grafting Density High Grafting

Conclusion

Applications of Bifurcating Brushes Recapitulation • Different than neutral brush due to chain-counterion complex nature

- f is charge fraction of chain, z valency, N number of segments, H brush height, T counterion cloud thickness and Σ normalized grafting density
- Ideal as stimuli-responsive surfaces because structure is <u>hyper-dependent</u> on environmental cues



Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields Simulations Low Grafting Density

Low Grafting Density Intermediate Grafting Density High Grafting Density

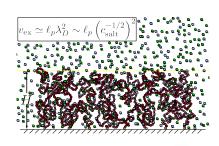
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Potential Applications of Bifurcating Brushes Recapitulation

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- f is charge fraction of chain, z valency, N number of segments, H brush height, T counterion cloud thickness and Σ normalized grafting density
- Ideal as stimuli-responsive surfaces because structure is <u>hyper-dependent</u> on environmental cues

High Salt Brush

- Salt screens electrostatics so brush is effectively electro-neutral
 - Screening inverse to salt concentration
 - H ~ N
 - $H \sim \Sigma^{1/3}$



Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields Simulations Low Grafting Density

Density
Intermediate
Grafting
Density
High Grafting
Density

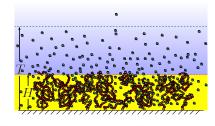
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Applications of Bifurcating Brushes Recapitulation

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- f is charge fraction of chain, z valency, N number of segments, H brush height, T counterion cloud thickness and Σ normalized grafting density
- Ideal as stimuli-responsive surfaces because structure is <u>hyper-dependent</u> on environmental cues

Pincus Brush (weakly charged)

- Brush is like a thin charged film and counterion cloud is attracted to it
 - $T \sim [\Sigma N]^{-1}$
 - $H \sim N^3$ strong dependence
 - H ~ Σ



Responsive Materials

Polyelectrolyte Brushes Perpendicular

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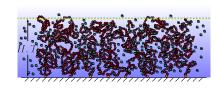
Applications of Bifurcating Brushes Recapitulation • Different than neutral brush due to chain-counterion complex nature

 f is charge fraction of chain, z valency, N number of segments, H brush height, T counterion cloud thickness and Σ normalized grafting density

 Ideal as stimuli-responsive surfaces because structure is <u>hyper-dependent</u> on environmental cues

Osmotic Brush (highly charged)

- Counterions are pulled into brush (polyelectrolyte / counterion complex)
 - T ≈ H
 - H ~ N
 - H does not have Σ dependence





Responsive Materials Polyelectrolyte Brushes

Perpendicular Low Grafting

Grafting High Grafting

Conclusion

Bifurcating

Osmotic Brushes as "Smart" Surfaces

- Ideal as stimuli-responsive surfaces because structure is hyper-dependent on environmental cues
- Favourable because form electroneutral films when unperturbed
- Easy, reproducible control over switching:
 - temperature
- salt

pH





Responsive Materials Polyelectrolyte Brushes

Perpendicular Low Grafting

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Conclusion

Bifurcating

Osmotic Brushes as "Smart" Surfaces

- Ideal as stimuli-responsive surfaces because structure is hyper-dependent on environmental cues
- Favourable because form electroneutral films when unperturbed
- Easy, reproducible and *fast* control over switching:
 - temperature
- salt

pH

electric fields



Langevin Dynamics

Simulations of Polyelectrolyte Brushes Subject to Normal Electric Fields



Polyelectrolyte Brushes Perpendicular Fields

Responsive Materials

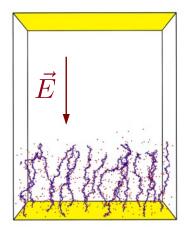
Simulations

Low Grafting Density Intermediate Grafting Density

High Grafting Density Conclusion

Potential Applications Bifurcating Brushes

Recapitulation





Langevin Dynamics

Simulations of Polyelectrolyte Brushes Subject to Normal Electric Fields





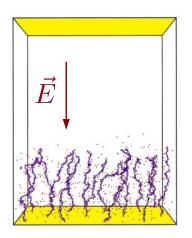
Responsive

Fields Simulations

Low Grafting

Grafting

Conclusion



- Low Grafting Density: $\Sigma = 0.0136$
- Intermediate Grafting Density: $\Sigma = 1.11$
- High Grafting Density:

 $\Sigma = 11.1$

Low Grafting Density

Stimuli-Responsive Materials

Polyelectrolyte Brushes Perpendicular

Fields Simulations

Low Grafting

Density Intermediate

Grafting Density High Grafting Density

Conclusion

Potential Applications Bifurcating Brushes

Recapitulation

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Low Grafting Density Brushes Subject to Normal Electric Fields





Responsive Materials

Polyelectrolyte Brushes

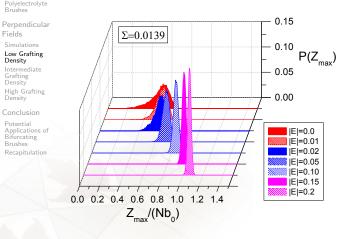
Fields Simulations

Low Grafting Density Intermediate

High Grafting

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Potential Bifurcating Brushes







Stimuli-Responsive Materials

Polyelectrolyte Brushes Perpendicular

Fields Simulations

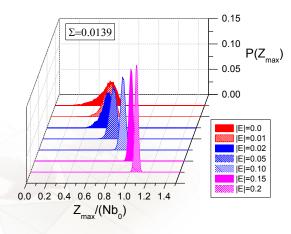
Low Grafting Density

Grafting Density High Grafting Density

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Brushes Recapitulatio



Two regimes:

• $|E| \lesssim 0.02$: Height is rather constant



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Polyelectrolyte Brushes Perpendicular

Fields

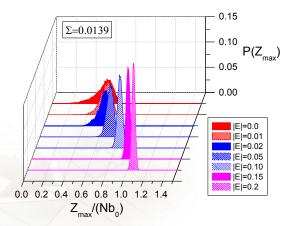
Low Grafting Density

Grafting Density High Grafting Density

Conclusion

Application Bifurcating

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Two regimes:

- $|E| \lesssim 0.02$: Height is rather constant
- $|E| \gtrsim 0.02$: Height increases with increased |E|





Responsive Materials Polyelectrolyte Brushes

Perpendicular Fields

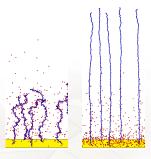
Simulations

Low Grafting Density

Grafting Density High Grafting

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Potential Applications of Bifurcating Brushes Recapitulation



Two regimes:

- Why not a steady rise?
- What does "critical" $|E^*|$ arise from?



Low Grafting DensityMonomer/Counterion Distributions — Low Fields



Stimuli-Responsive Materials

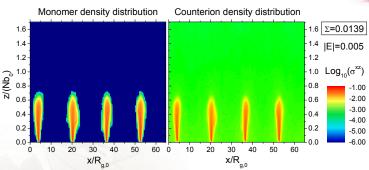
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Density Intermediate Grafting Density High Grafting

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Applications o Bifurcating Brushes Recapitulation

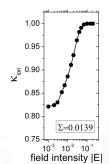


- Counterion distribution corresponds to monomer distribution
- Not perfectly electroneutral background probability
- Low grafting density brush not quite ideal osmotic brush



Low Grafting DensityCounterion Confinement and Condensation





In weak field limit, 82% of counterions confined to brush region (z \leq Z_{max})

Low Grafting Density Intermediate Grafting Density High Grafting Density Conclusion Potential Applications of Bifurcating

Brushes

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Simulations



Responsive Materials

Brushes Perpendicular

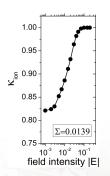
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Low Grafting Density

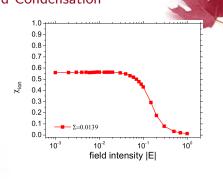
Grafting High Grafting

Conclusion

Low Grafting Density Counterion Confinement and Condensation



In weak field limit, 82% of counterions confined to brush region $(z < Z_{max})$



- 56% *condensed* (closer than λ_B to a chain)
- Manning theory for free chain predicts $\chi_{\rm ion} = 1 - b_0/\lambda_B = 61\%$

Responsive Materials

Perpendicular

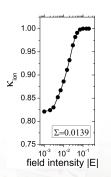
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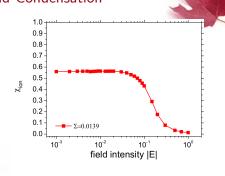
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Although not perfect, screening is effective for fields $\lesssim |E^*| \simeq 0.02$

Responsive Materials

Perpendicular

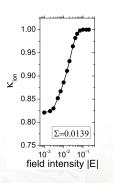
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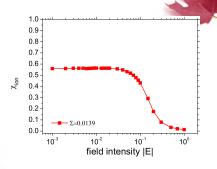
Grafting

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Low Grafting Density

Counterion Confinement and Condensation





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- When $|E| \ll |E^*|$, counterion and monomer distributions correspond
- When $|E| \geq |E^*|$, counterions forced down thus superimposing exponential/Boltzmann distribution
- When $|E| \gg |E^*|$, positive monomers hardly perturb exponential distribution



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Responsive Materials Polyelectrolyte Brushes

Perpendicular Fields

Simulations Low Grafting Density

Intermediate Grafting Density

Density High Grafting Density

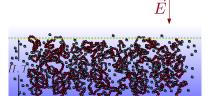
Conclusion Potential

Applications of Bifurcating Brushes Recapitulation

Scaling Argument

Chain stretches once energy gained by moving charge a *characteristic distance*, ℓ , is greater than $k_{\rm B}T$

$$E^*e\ell \sim k_BT \qquad \rightarrow \qquad E^* \sim \frac{k_BT}{e}$$





Polyelectrolyte Brushes

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Fields Simulations

Low Grafting Density

Grafting Density High Grafting Density

Conclusion

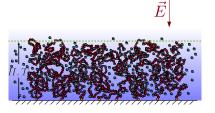
Potential Applications of Bifurcating Brushes Recapitulation

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But what is the *characteristic distance*?





Perpendicular Fields

Simulations Low Grafting Density

Grafting

High Grafting

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Potential Bifurcating Brushes

Scaling Argument

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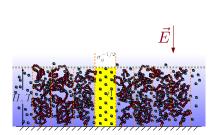
$$E^*e\ell \sim k_BT \qquad \rightarrow \qquad E^* \sim \frac{k_BT}{e}$$

But what is the characteristic distance?

In mean-field sense, ℓ is average distance between charges

$$\ell \sim \left(\frac{H\sigma_g^{-1}}{N}\right)^{1/3}$$





Low Grafting Density

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Bifurcations of Bifurcations of Brushes

Recapitulatio

Critical Field



Scaling Result

$$E^* \sim \frac{k_{\rm B}T}{e} \left(\frac{N\sigma_{\rm g}}{H}\right)^{1/3}$$

 $\sim \Sigma^{1/3}$



Responsive Materials

Polyelectrolyte Brushes Perpendicular

Fields Simulations

Low Grafting

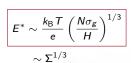
Density

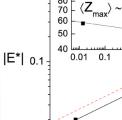
High Grafting

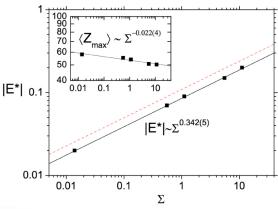
Potential Bifurcating

Brushes

Scaling Result









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Responsive Materials

Polyelectrolyte Brushes Perpendicular

Fields Simulations

Low Grafting Density

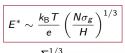
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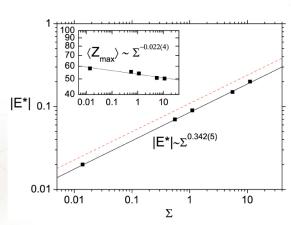
Bifurcating Brushes

Scaling Result



 $\sim \Sigma^{1/3}$

If $H = H(\Sigma)$ (as observed) then $E^* \sim \Sigma^{0.341}$.





Low Grafting Density Conclusion

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Low Grafting Density

Intermediate Grafting Density High Grafting Density

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Potential Applications Bifurcating

Brushes Recapitulation

Conclusion About Low Grafting Density:

- There are two regimes:
 - $|E| < |E^*|$: brush height is constant
 - $|E| > |E^*|$: brush height increases
- $E^* \sim \Sigma^{1/3}$



Intermediate Grafting Density

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Intermediate Grafting Density Brushes Subject to Normal Electric Fields



Intermediate Grafting DensityBrush Height





Responsive Materials

Simulations Low Grafting Density

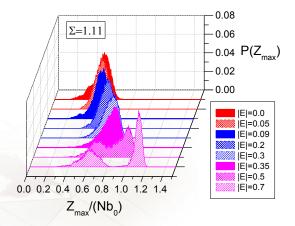
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High Graftin Density

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Potential Application Bifurcating Brushes

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Three regimes:



Intermediate Grafting DensityBrush Height





Polyelectrolyte Brushes

Perpendicular Fields

Low Grafting Density

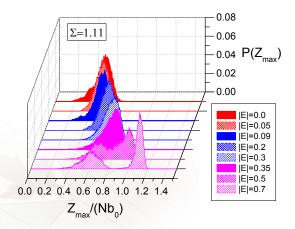
Intermediate Grafting Density

High Grafting Density

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Three regimes:

- Height constant at low fields $|E^*| \simeq 0.09$
- Height increases at intermediate fields



Intermediate Grafting DensityBrush Height



Stimuli-Responsive Materials

Polyelectrolyte Brushes

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Low Grafting Density Intermediate

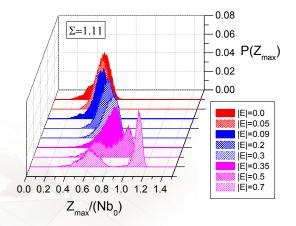
Grafting Density

High Grafting Density

Conclusion

Application Bifurcating

Brushes Recapitulation



Three regimes:

- Height constant at low fields $|E^*| \simeq 0.09$
- Height increases at intermediate fields
- Splitting at second critical field $|E^{**}| \simeq 0.35$



Intermediate Grafting Density Monomer/Counterion Distributions — Low Fields

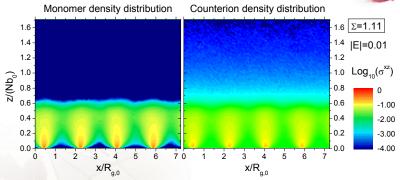




Intermediate Grafting Density High Grafting

Responsive Materials

Conclusion



- At intermediate densities brush is closer to ideally osmotic
- Most (97% in zero field) counterions reside within brush
- More homogeneous and effectively electroneutral



Stimuli-Responsive Materials

Polyelectrolyte Brushes

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Simulations Low Grafting Density Intermediate

Grafting Density High Grafting

High Graftin Density

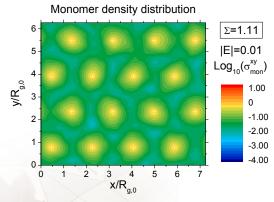
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Intermediate Grafting DensityMonomer/Counterion Distributions — Low Fields





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Stimuli-Responsive

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Low Grafting Density Intermediate

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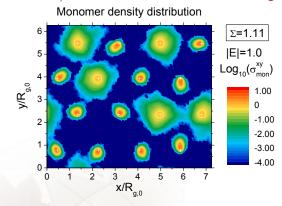
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Intermediate Grafting Density Monomer/Counterion Distributions — High Fields







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Density

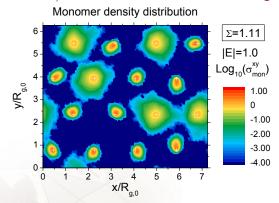
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Brushes Recapitulation

Intermediate Grafting Density Monomer/Counterion Distributions — High Fields





- The population bifurcates into
 - few unstretched chains
 - many highly stretched chains



Intermediate Grafting DensityBrush Height – Bifurcation





Stimuli-

Responsive Materials

Simulations Low Grafting

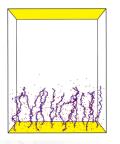
Intermediate Grafting Density

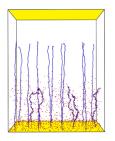
High Grafting Density

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Applications Bifurcating Brushes

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• Why does *bifurcation* occur at $|E^{**}|$?





Polyelectrolyte Brushes Perpendicular Fields

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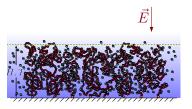
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Scaling Argument

Second critical field $|E^{**}|$ is the minimum for which





Polyelectrolyte Brushes Perpendicular

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Low Grafting Density Intermediate

Grafting Density High Grafting

High Graftii Density

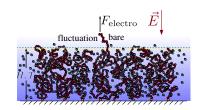
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Applications Bifurcating Brushes

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Scaling Argument

Second critical field $|E^{**}|$ is the minimum for which $F_{\rm electro}=zqE$ on segment that has fluctuated out of the protective counterion cloud





Brushes Perpendicular Fields

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Simulations Low Grafting

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Density High Grafting Density

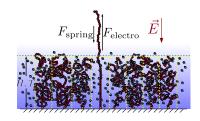
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Brushes Recapitulation

Scaling Argument

Second critical field $|E^{**}|$ is the minimum for which $F_{\rm electro}=zqE$ on segment that has fluctuated out of the protective counterion cloud is greater than the elastic restoring force $F_{\rm spring}=H/Na^2$





Materials

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Conclusion Potential

Bifurcating Brushes

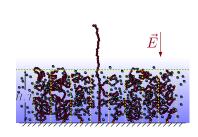
Scaling Argument

Second critical field $|E^{**}|$ is the minimum for which $F_{\text{electro}} = zqE$ on segment that has fluctuated out of the protective counterion cloud is greater than the elastic restoring force $F_{\text{spring}} = H/Na^2$

$$zqE^{**} \sim \frac{H}{Na^2}$$

$$E^{**} \sim \frac{1}{qa} \left(\frac{f}{z^3}\right)^{1/2} = const.$$

since $H \simeq Na(f/z)^{1/2}$ in an osmotic brush.





Responsive Materials

Perpendicular Fields

Low Grafting Intermediate

Grafting Density High Grafting

Conclusion

Bifurcating Brushes

Scaling Argument

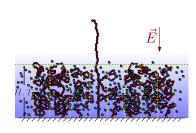
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$$E^{**} \sim \frac{1}{qa} \left(\frac{f}{z^3}\right)^{1/2} = const.$$

since $H \simeq Na(f/z)^{1/2}$ in an osmotic brush.

 E** is not predicted to scale with Σ, nor N



Intermediate Grafting Density Conclusion



Responsive Materials

Perpendicular

Fields

Low Grafting

Intermediate Grafting Density

High Grafting

Conclusion

Bifurcating

Conclusion About Intermediate Grafting Density:

- There are three regimes:
 - $|E^*| < |E|$: brush height is constant
 - $|E^*| < |E| < |E^{**}|$: brush height increases
 - $|E^{**}| < |E|$: brush *bifurcates*
- $|E^{**}| \sim \Sigma^0$

Responsive Materials

Polyelectrolyte Brushes

Perpendicular

Fields

Simulations Low Grafting Grafting

High Grafting Density

Conclusion

Bifurcating Brushes

Potential Recapitulation

High Grafting Density Brushes Subject to Normal Electric Fields



High Grafting Density Immediate Bifurcation





Responsive Materials

Fields Simulations

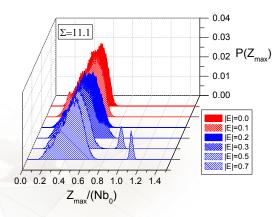
Low Grafting

High Grafting Density

Conclusion

Potential

Bifurcating Brushes



Bifurcates but ... $E^*(\Sigma) = E^{**}$ at high Σ



High Grafting Density Immediate Bifurcation





Polyelectrolyte Brushes

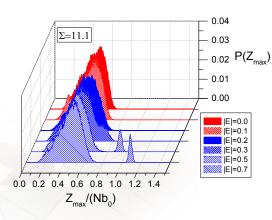
Perpendicular Fields

Low Grafting Grafting

High Grafting Density

Conclusion

Bifurcating Brushes



Bifurcates but . . . $E^*(\Sigma) = E^{**}$ at high Σ

- Increasing Σ increases F*
- but E^{**} nearly constant
- Therefore, immediate bifurcation at high Σ

High Grafting Density Immediate Bifurcation

Responsive Materials Brushes

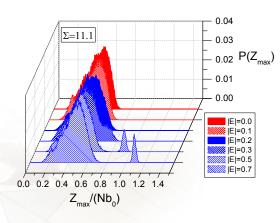
Perpendicular Fields

Low Grafting Grafting

High Grafting Density

Conclusion

Bifurcating Brushes



Bifurcates but . . . $E^*(\Sigma) = E^{**}$ at high Σ

- Increasing Σ increases F*
- but E^{**} nearly constant
- Therefore, *immediate* bifurcation at high Σ

Fully stretched chains now the *minority*



High Grafting Density Minority



Polyelectrolyte Brushes Perpendicular Fields

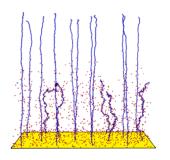
Responsive Materials

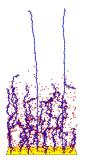
Simulations Low Grafting Grafting

High Grafting Density

Conclusion

Potential Bifurcating Brushes





- When |E| > |E**|: Majority stretched if $\Sigma = 1.11$ but *minority* stretched if $\Sigma = 11.1$
- Why are more relaxed and unstretched compared to intermediate Σ ?



Increased Counterion Confinement and Condensation



Polyelectrolyte Brushes

Perpendicular Fields

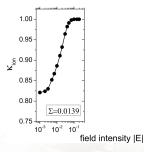
Low Grafting Density Intermediate Grafting Density

High Grafting Density

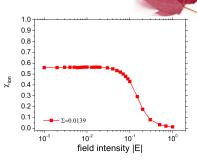
Conclusion

Application Bifurcating

Brushes Recapitulation



 In weak fields and low grafting density, 82% of counterions confined to brush



 In weak fields and low grafting density, 56% of counterions condensed

Increased Counterion Confinement and Condensation

Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields

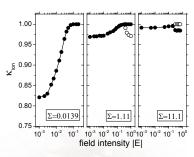
Low Grafting Density Intermediate Grafting

High Grafting Density

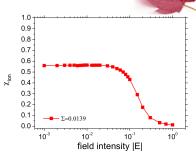
Conclusion

Application Bifurcating

Brushes Recapitulation



- In weak fields and low grafting density, 82% of counterions confined to brush
- Jumps to 97% when $\Sigma = 1.11$ and 99% when $\Sigma = 11.1$



 In weak fields and low grafting density, 56% of counterions condensed

Increased Counterion Confinement and Condensation

Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields

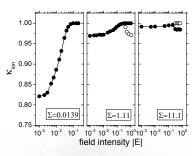
Low Grafting Density Intermediate Grafting

High Grafting Density

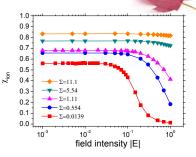
Conclusion

Potential Applications Rifurcating

Brushes Recapitulation



- In weak fields and low grafting density, 82% of counterions confined to brush
- Jumps to 97% when $\Sigma = 1.11$ and 99% when $\Sigma = 11.1$



- In weak fields and low grafting density, 56% of counterions condensed
- Increases to 78% when $\Sigma=1.11$ and 84% when $\Sigma=11.1$

Increased Counterion Confinement and Condensation

Stimuli-Responsive Materials

Polyelectrolyte Brushes

Perpendicular Fields

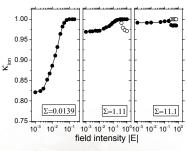
Low Grafting Density Intermediate Grafting Density

High Grafting Density

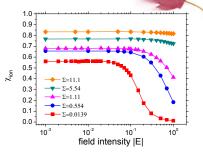
Conclusion

Applications Bifurcating

Brushes Recapitulation



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Assuming local neutrality becomes more accurate at higher grafting densities.

Increased Counterion Confinement and Condensation

Responsive Materials

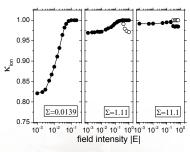
Brushes

Perpendicular

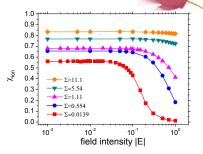
Low Grafting Grafting

High Grafting Density

Conclusion



- In weak fields and low grafting density, 82% of counterions confined to brush
- Jumps to 97% when $\Sigma = 1.11$ and 99% when $\Sigma = 11.1$



- In weak fields and low grafting density, 56% of counterions condensed
- Increases to 78% when $\Sigma = 1.11$ and 84% when $\Sigma = 11.1$

Assuming local neutrality becomes more accurate at higher grafting densities.

Less chains bare and liable to be fully stretched.

High Grafting Density Conclusion



Stimuli-Responsive Materials

Brushes

Perpendicular Fields

Low Grafting Density Intermediate Grafting

High Grafting Density

Conclusion

Potential Applications of Bifurcating Brushes Recapitulation Conclusion About High Grafting Density:

- At high grafting densities, $|E^*| = |E^{**}|$
- Fully stretched population becomes minority

Potential Applications of Bifurcating Brushes

*

Original Motivation:

Polyelectrolyte brushes as field controlled gates



Responsive Materials

Grafting Density High Grafting

Density

Conclusion

Conclusion Potential

Applications of Bifurcating Brushes

Recapitulatio



Potential Applications of Bifurcating Brushes



Original Motivation:

Polyelectrolyte brushes as field controlled gates but bifurcation suggests an array of unexpected possiblities.



Responsive

Perpendicular Fields

Simulations Low Grafting Density

Grafting Density High Grafting

Conclusion

Potential Applications of Bifurcating Brushes

Recapitulation

Potential Applications of Bifurcating Brushes



Original Motivation:

Polyelectrolyte brushes as field controlled gates *but* bifurcation suggests an array of unexpected possiblities.

Novel MEMS Components:

Control flow resistance

Responsive Materials

Perpendicular

Simulations Low Grafting Density

Intermediate Grafting Density High Grafting Density

Conclusion

Potential Applications of Bifurcating Brushes

Recapitulatio



Potential Applications of Bifurcating Brushes



Original Motivation:

Polyelectrolyte brushes as field controlled gates but bifurcation suggests an array of unexpected possiblities.

Novel MEMS Components:

- Control flow resistance
- Filtration by number of rods

Low Grafting Density Intermediate Grafting

Perpendicular

Responsive Materials

Grafting Density High Graftin Density

Conclusion Potential

Applications of Bifurcating Brushes

Recapitulation



Potential Applications of Bifurcating Brushes



Original Motivation:

Polyelectrolyte brushes as field controlled gates but bifurcation suggests an array of unexpected possiblities.

Novel MEMS Components:

- Control flow resistance
- Filtration by number of rods
- Control the surface friction

Grafting

Responsive Materials

Perpendicular

Low Grafting

Conclusion Potential

Applications of Bifurcating Brushes



Potential Applications of Bifurcating Brushes



Perpendicular

Responsive

Simulations
Low Grafting

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Intermediate Grafting Density

Density High Graftin Density

Conclusion Potential

Applications of Bifurcating Brushes Recapitulation

Original Motivation:

Polyelectrolyte brushes as field controlled gates but bifurcation suggests an array of unexpected possiblities.

Novel MEMS Components:

- Control flow resistance
- Filtration by number of rods
- Control the surface friction
- Utilizing polyampholytes or end-labeled chains may allow choosing which chains stretch

Potential Applications of Bifurcating Brushes



Perpendicular

Responsive

Simulations Low Grafting

Intermediate Grafting Density High Grafting Density

Conclusion Potential

Applications of Bifurcating Brushes Recapitulation

Original Motivation:

Polyelectrolyte brushes as field controlled gates but bifurcation suggests an array of unexpected possiblities.

Novel MEMS Components:

- Control flow resistance
- Filtration by number of rods
- Control the surface friction
- Utilizing polyampholytes or end-labeled chains may allow choosing which chains stretch
- Fishing the tethering and subsequent trapping within the interior of the brush of analytes by alternating fields



Responsive

Materials

Brushes Perpendicular

Fields

Low Grafting

Grafting High Grafting

Conclusion Potential

Brushes

Applications of Bifurcating









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Gary Slater

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- Henk de Haan
- Martin Bertrand
- Yuguo Tao
- David Sean
- Zheng Ma

Webpages

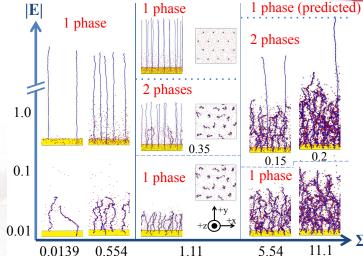
- Gary Slater: www.science.uottawa. ca/~gslater
- Tyler Shendruk: www.tnshendruk.com



Recapitulation

Structure of highly charged polyelectrolyte brushes in the no-salt limit,

subject to normal electric fields:



Intermediate

High grafting density



Responsive

Perpendicular Fields

Simulations Low Grafting Grafting

High Grafting

Conclusion Potential Bifurcating

Recapitulation

Materials Polyelectrolyte Brushes

> Structure of polyelectrolyte brushes subject to normal electric fields. Langmuir, 29(7): 2359-2370, 2013.

Low